## KAJIHARA LAB.

## [Manufacturing and THz microscopy]

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Manufacturing Science Fundamentals

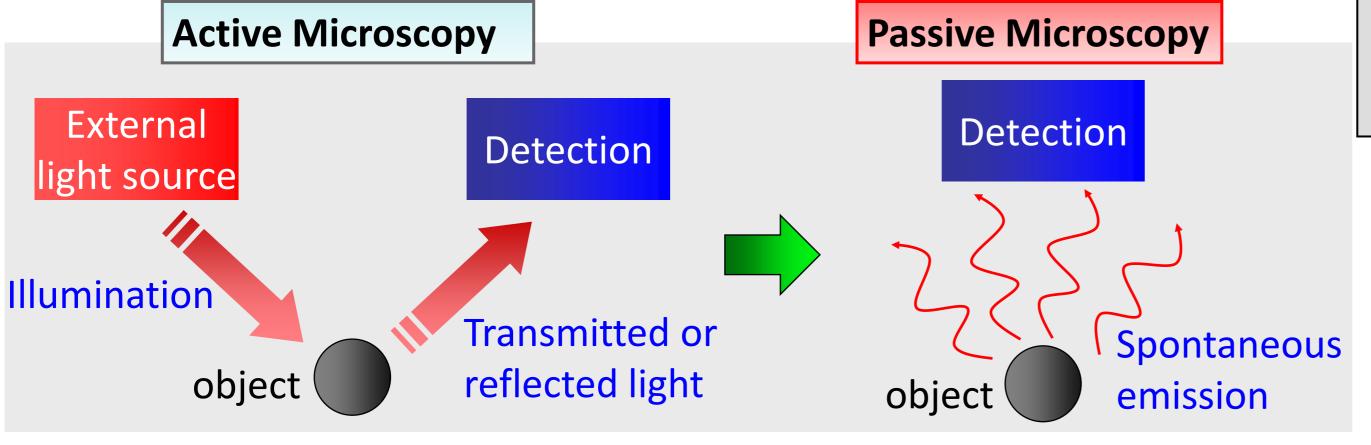
Department of precision engineering

## Nano-scale THz measurement

Visualizing local phenomena on material's surface

Terahertz wave (wavelength: 10  $\mu$ m  $\sim$  1 mm) contains many important spectra of matters due to molecular vibration, lattice phonon, and biomolecular motion. We are developing a near-field microscope, which "passively (without external illumination)" detects spontaneous THz photons originated from localized phenomena at "nanoscale" resolution. We are also developing a new manufacturing technique

- ◆Passive THz near-field microscopy without external illumination (spatial resolution = 60 nm)
- ◆Visualization of thermal evanescent field on objects
- ◆Non-destructive THz nano-thermometry
- ◆Novel manufacturing technique

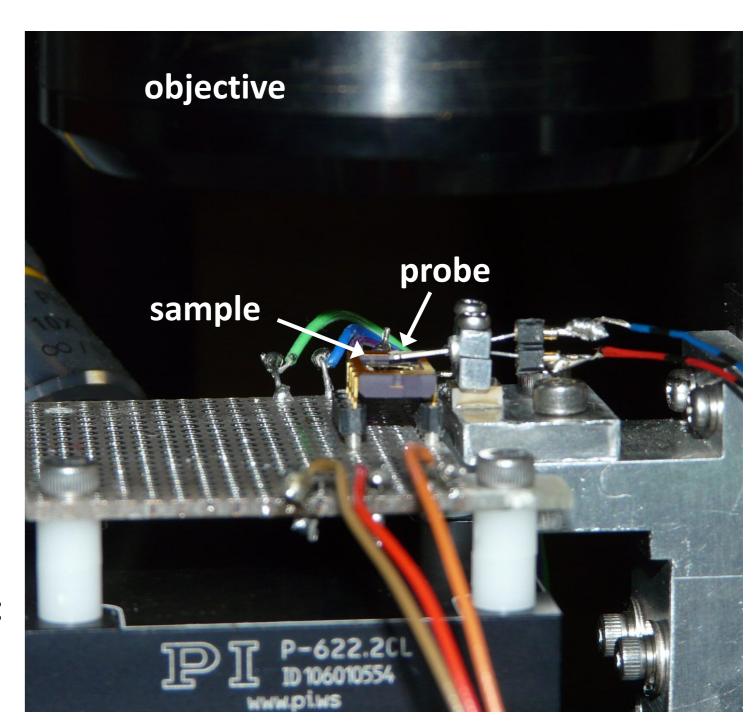


CSIP detector
(4.2 K)

Ge
objective

W probe
evanescent
wave
sample

NiCr



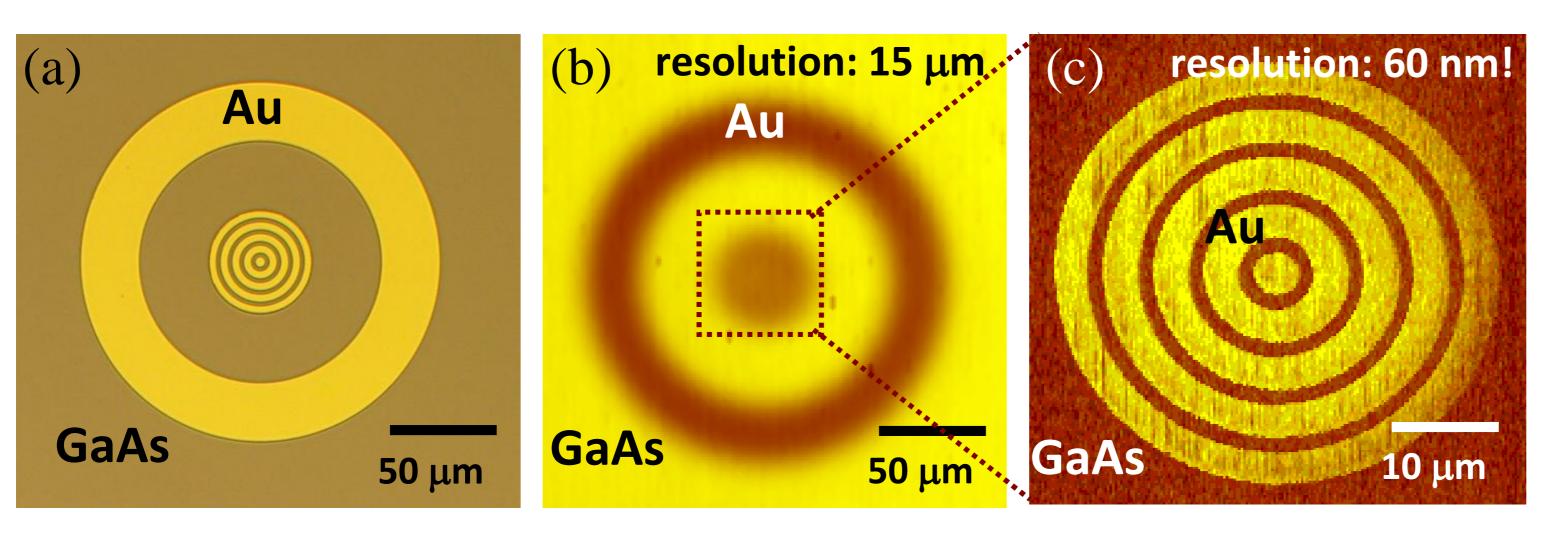
Far-field [nA]

270

Fig.1 Conventional active measurement and our passive measurement

Fig. 2 Passive THz near-field microscope

 $\lambda$ : 14.5  $\mu$ m



conventional far-field 265 260 255 **2** μm Near-field [pA] 600 500 Higher current density passive 400 near-field 300 200 SiO

Fig.3 (a) Microscope image (b) Passive far-field image (c) Passive near-field image

Fig. 4 Current density distribution mapped with THz nano-thermometry